

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Franz LAERMER et al.
Serial No. : 10/530,612
Filed : December 30, 2005
For : **PLASMA SYSTEM AND METHOD FOR
ANISOTROPICALLY ETCHING STRUCTURES
INTO A SUBSTRATE**

Art Unit : 1713
Examiner : Maki A. ANGADI
Confirmation No. : 6739
Customer No. : 26646

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being electronically
deposited to the USPTO via the Office electronic filing system on

Date: June 18, 2010

Signature: /Kevin Kambo/
Kevin Kambo

RESPONSE TO NON-FINAL OFFICE ACTION

SIR:

In response to the Office Action of April 9, 2010, for which a
three-month response period expires on July 9, 2010, please reconsider the
above-identified application based on the following:

Amendments to the Claims are reflected in the **Listing of Claims**,
which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.

While no fees are believed to be due, the Commissioner is authorized,
as appropriate and/or necessary, to charge any fees or credit any
overpayment to **Deposit Account No. 11-0600**.